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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Min-Lung HUANG Confirmation No: 8488
Appl. No. : 10/820,829
Filed : April 9, 2004
Title : UNDER BUMP METALLIZATION STRUCTURE OF A
SEMICONDUCTOR WAFER

TC/A.U. : 2814
Examiner : P. X. Cao

Docket No.: : HUAN3260/REF
Customer No: : 23364

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the Official Action of January 4, 2004, in connection with the above identified application.

The Official Action is a restriction requirement in which it is urged that there are two separate and distinct species claimed in this application. Applicants elect the Group I species which includes claims 1-10, without traverse. Applicants reserve the right to file a divisional application on the non-elected species at a later time.

In view of the election of the Group I species, without traverse, an early and favorable action on the merits is now believed to be in order and is most respectfully requested.

Respectfully submitted,
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